In the Specification:

Please replace paragraph **[0026]** with the following rewritten paragraph:

During system calibration, a flat target with a substantially uniform reflectivity is positioned at a distance from the camera system. For a vertical epipolar system (i.e. the light projector is vertically aligned with the camera relative to the image frame), the matrix image shifts up and down as target distance varies. A routine for locating and labeling beams of a beam matrix is disclosed in U.S. Patent ~~Application Serial No. _____ (DP 309576/DEL01-P-464)~~ No. 7,002,699, entitled "IDENTIFICATION AND LABELING OF BEAM IMAGES OF A STRUCTURED BEAM MATRIX," ~~filed _____~~, the entire disclosure of which is hereby incorporated by reference in its entirety.

Please replace paragraph **[0037]** with the following rewritten paragraph:

The estimation of current laser and LED light levels are conducted in the areas that are defined by the structured laser beams. The location and identification of those beams can be determined from the structured light configuration (Spatial Encoding Method) as described in U.S. Patent ~~Application Serial No. _____ (DP 305117)~~ No. 6,762,427 entitled "OBJECT SURFACE CHARACTERIZATION USING OPTICAL TRIANGULATION AND A SINGLE CAMERA," ~~filed _____~~, the entire disclosure of which is hereby incorporated herein by reference in its entirety. As is disclosed in ~~DP 309576/DEL01-P-464~~ U.S. Patent No. 7,002,699, the method first finds the structured laser beams in the image plane. Over these beam areas, the average LED light level B and the averaged laser light level A are then calculated. The LED light level estimation uses the image frame when LED light is the only illumination. The laser light level estimation uses differential frames between the image when both the LED and the laser are turned on and the image when only LED illumination is turned on.